

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: §
Tony Kroeker §
Serial No.: Unknown §
Filed: Herewith §
Continuation of Serial No. 09/161,970 §
Continuation Filed: Sept. 28, 1998 §
For: Single Wafer Load Lock With §
Internal Wafer Transport §

Group Art Unit: Unknown
Examiner: Unknown

CERTIFICATION UNDER 37 CFR 1.10	
I hereby certify that this correspondence is being deposited with the United States Postal Service on this date, <u>6-4-01</u> , in an envelope as "Express Mail Post Office to Addressee," mailing label no. <u>EL704518435US</u> , addressed to: Assistant Commissioner for Patents, Box PATENT APPLICATION, Washington, D.C. 20231.	
Date <u>6-4-01</u>	Signature <u>Beth Mahoney</u>

Assistant Commissioner of Patents
Washington, D.C. 20231

Dear Sir:

PRELIMINARY AMENDMENT

Prior to examination of the above referenced application, the Applicant requests that the application be amended as follows:

In the claims:

Please cancel claims 1-45, without prejudice, and add the following claims:

46. (New) A semiconductor processing system, comprising:
a pod loader;
a mini-environment having a robot disposed therein;
one or more load lock chambers connected to the mini-environment; and
one or more process chambers connected to the one or more load lock chambers, wherein each load lock chamber is connected to a single process chamber.
47. (New) The system of claim 46, wherein each load lock chamber comprises:
an enclosure having a bottom, a lid and sidewalls defining a chamber cavity; and